

PATENT ASSIGNMENT COVER SHEET

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SUBMISSION TYPE:	NEW ASSIGNMENT
NATURE OF CONVEYANCE:	ASSIGNMENT
CONVEYING PARTY DATA	
Name	Execution Date
RYUSEI TERASHIMA	04/05/2022
TAKUMI YOSHINO	04/05/2022
TSUNEO TERASAWA	04/05/2022
RECEIVING PARTY DATA	
Name:	SHIN-ETSU CHEMICAL CO., LTD.
Street Address:	4-1, MARUNOUCHI 1-CHOME
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PROPERTY NUMBERS Total: 1	
Property Type	Number
Application Number:	17712031
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ATTORNEY DOCKET NUMBER:	633506-3 DNZ/JF
NAME OF SUBMITTER:	DAIFEI ZHANG 79356
SIGNATURE:	/Daifei Zhang 79356/
DATE SIGNED:	09/09/2022
Total Attachments: 6	
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Ladas ref. 633506

U.S. ASSIGNMENT

For good and valuable consideration, the receipt of which is hereby acknowledged, ASSIGNORS:

Ryusei TERASHIMA, c/o Shin-Etsu Chemical Co., Ltd., New Functional Materials Research Center, 28-1, Nishifukushima, Kubiki-ku, Joetsu-shi, Niigata 942-8601 Japan

Takumi YOSHINO, c/o Shin-Etsu Chemical Co., Ltd., New Functional Materials Research Center, 28-1, Nishifukushima, Kubiki-ku, Joetsu-shi, Niigata 942-8601 Japan

Tsuneo TERASAWA, c/o Shin-Etsu Chemical Co., Ltd., New Functional Materials Research Center, 28-1, Nishifukushima, Kubiki-ku, Joetsu-shi, Niigata 942-8601 Japan

hereby, sell, assign and transfer to ASSIGNEE, Shin-Etsu Chemical Co., Ltd., a Corporation, having offices located at 4-1, Marunouchi 1-chome, Chiyoda-ku, Tokyo 100-0005 Japan, and the successors, assigns, and legal representatives of the ASSIGNEE all of their right, title, and interest for the United States and its territorial possessions in and to any and all improvements which are disclosed in the INVENTION entitled:

DEFECT INSPECTION APPARATUS, METHOD FOR INSPECTING DEFECT, AND METHOD FOR MANUFACTURING PHOTOMASK BLANK

which is found in

Japanese Patent Application No. 2021-063981 filed on April 5, 2021

and US Patent Application No. 17/712031 (patent application number) filed on April 1, 2022 (date)

and any legal equivalents thereof, including the right to claim priority and, in and to all Letters Patent to be obtained for said INVENTION by the above application(s) and any continuation(s), division(s), continuation(s)-in-part, extension(s), conversion(s), and substitute(s) thereof, and any reissue(s), reexamination(s), and extension(s) of said Letters Patent.

ASSIGNORS hereby agree that no assignment, sale, agreement or encumbrance has been or will be made or entered into which would conflict with this Assignment.

ASSIGNORS further agree that ASSIGNEE will upon its request, be provided promptly with all pertinent facts and documents relating to said invention and said Letters Patent and legal equivalents as may be known and accessible to ASSIGNORS and will testify as to the same in any interference, post grant, inter partes review, litigation, or proceeding relating thereto and will promptly execute and deliver to ASSIGNEE or its legal representatives, any and all papers, instruments, and affidavits required to apply for, obtain, maintain, issue and enforce said application(s), said INVENTION, and said Letters Patent and said equivalents thereof which may be necessary or desirable to carry out the purposes thereof.

ASSIGNORS request the Commissioner of Patents and Trademarks to issue said Letters Patent of the United States and any reissue(s) and extension(s) thereof to the ASSIGNEE.

An attorney of record for the matters herein is authorized and requested by the execution of this

Ladas ref. 633506

Assignment to insert into this Assignment the filing date(s), serial number(s) and title(s) of said application(s) when known.

Ryusei TERASHIMA
Ryusei TERASHIMA

April 5, 2022
Date

Takumi YOSHINO
Takumi YOSHINO

April 5, 2022
Date

Tsunao TERASAWA
Tsunao TERASAWA

April 5, 2022
Date

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Ryusei TERASHIMA

April 5, 2022
Date

Takumi Yoshino
Takumi YOSHINO

April 5, 2022
Date

Tsuneo TERASAWA

April 5, 2022
Date

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Takumi YOSHINO

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Date

Tsunao Terasawa
Tsunao TERASAWA

April 5, 2022
Date